

**ABSTRACT****A MATERIAL FOR USE IN A MEMS DEVICE, A METHOD OF MAKING THE MATERIAL AND A MEMS DEVICE INCLUDING THE MATERIAL**

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A multi-layered material for use in a microelectromechanical system (MEMS) device includes six layers of magnetisable Co-Ni-Re-W-P material, each adjacent pair of magnetisable layers have a respective layer of non-magnetisable, electrically-conductive Cu therebetween. The material is formed on a seed layer of Au, which in turn is formed on a glass substrate coated with a thin Cr coating. The layers of non-magnetisable material are approximately 1 μm thick. The layers of Cu are also approximately 1 μm thick.

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(Figure 1)

